

Amendment and Response Under 37 C.F.R. 1.116

Applicant: Craig K. Carlson-Stevermer

Serial No.: 10/622,849

Filed: July 18, 2003

Docket No.: A126.114.102

Title: WAFER STAGING PLATFORM**IN THE ABSTRACT**

Please replace the paragraph beginning at page 10, line 5 with the following rewritten paragraph:

A wafer staging platform for ~~use with equipment such as a~~ wafer inspection system for inspecting of semiconductors or like substrates and method of handling wafers. The platform and related method is designed to reduce the amount of time needed to exchange wafers on a processing tool.- The staging platform can include a vacuum-assisted feature. The method of handling includes simultaneously processing a plurality of wafers, during which the staging platform is employed to temporarily store wafer(s) in close proximity to a next in line station.